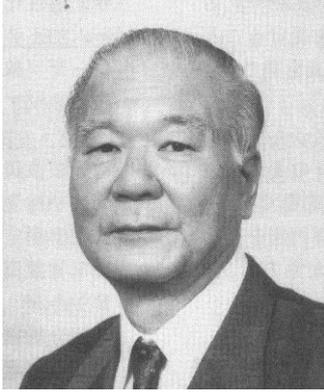
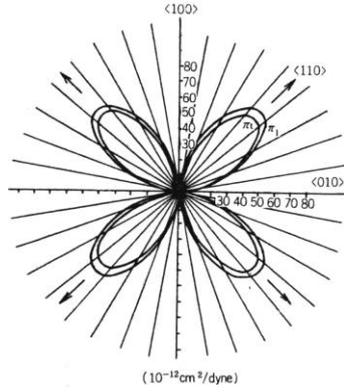


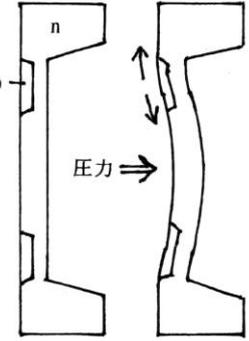
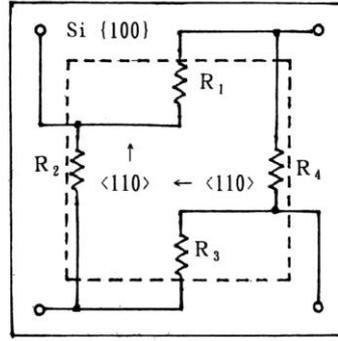
ピエゾ抵抗型圧力センサ



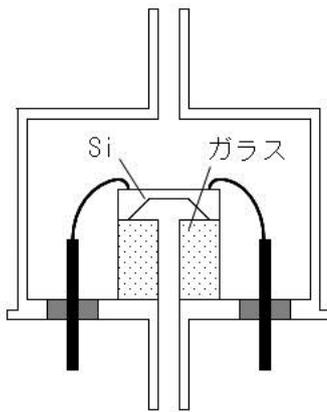
五十嵐 伊勢美 氏
(豊田中央研究所)



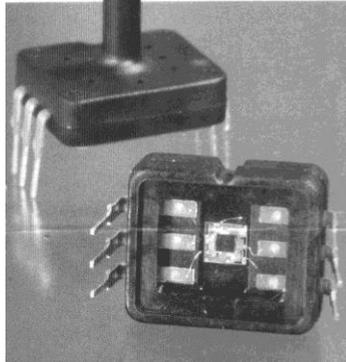
(100)面 p 型 Si のピエゾ抵抗係数
$\langle 110 \rangle$方向で最大



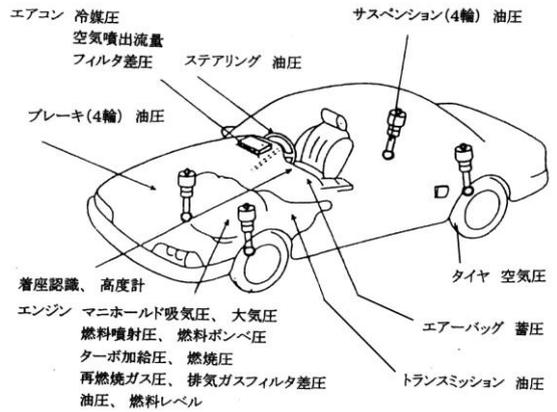
Si 感圧ダイアフラムに p 型拡散層のピエゾ抵抗を
配置したピエゾ抵抗型圧力センサ



圧力センサのパッケージング例



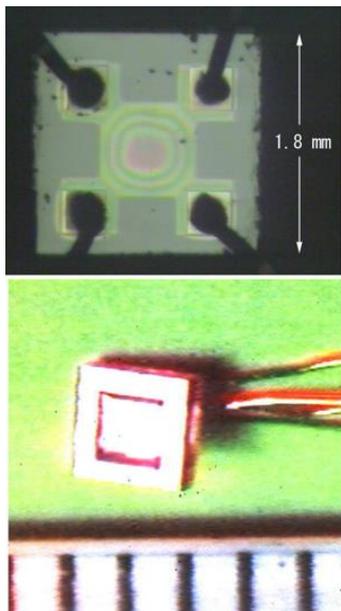
(株)フジクラの圧力センサ



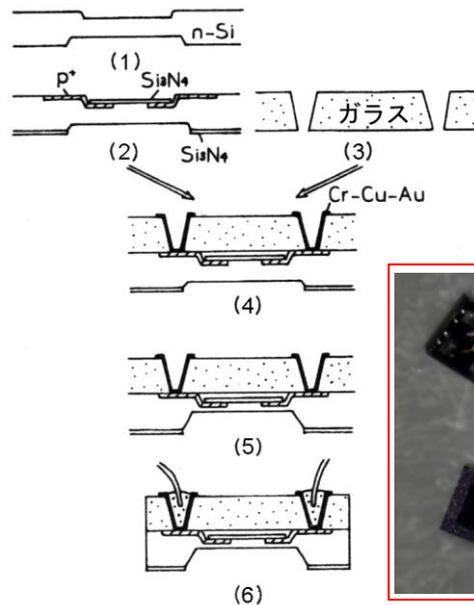
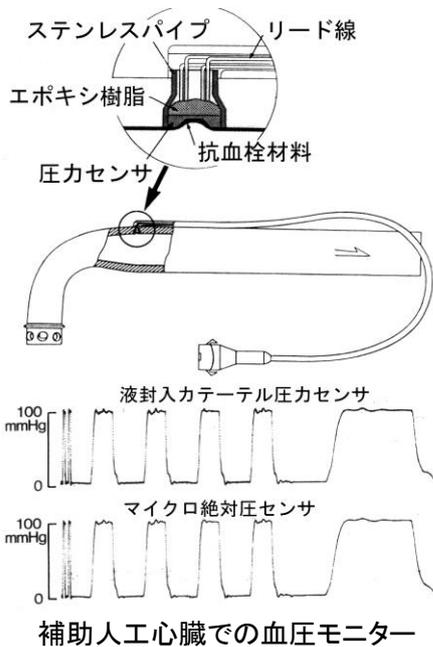
自動車に使われる圧力センサ

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O.N.Tufle (Honeywell), Silicon Diffused-element Piezoresistive Diaphragms, J. of Applied Physics, 33 (1962) pp.3322-3327

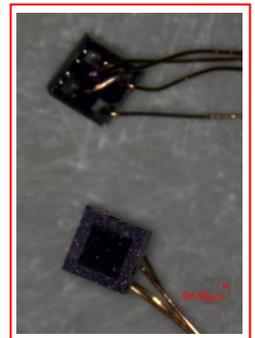
ピエゾ抵抗型絶対圧センサ



写真



製作工程



参考文献：M.Esashi, Y.Matsumoto and S.Shoji, Absolute Pressure Sensors by Air-tight Electrical Feedthrough Structure, Sensors and Actuators, A21-A23 (1990) pp.1048-1052